

1_SiN_dep					
SUBROUTINE	STEPS				
N2_Gas_Prep	N2_Gas_Prep				
		Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam voltage=0	Beam voltage=0		Fixture Tilt Angle=40
		Beam current=0	Beam current=0		Fixture Rotation Speed=20rpm
		Ignition RF Power=0	Ignition RF Power=0		
		Suppressor Voltage=0	Suppressor Voltage=0	PM1	Process time
		PBN Flowrate=5	PBN Flowrate=5	Si	10sec
		K Factor=0	K Factor=0		substrate=close
		Gas Values	Gas Values		target=close
		PM1	PM1		
		Ar=0	Ar=0		
		Xe=0	O2=0	Target angle=55	
		N2=0	N2=5		
N2_Gas_Shutoff					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam voltage=0	Beam voltage=0		Fixture Tilt Angle=40
		Beam current=0	Beam current=0		Fixture Rotation Speed=20rpm
		Ignition RF Power=0	Ignition RF Power=0		
		Suppressor Voltage=0	Suppressor Voltage=0	PM1	Process time
		PBN Flowrate=5	PBN Flowrate=5	Si	10sec
		K Factor=0	K Factor=0		substrate=close
		Gas Values	Gas Values		target=close
		PM1	PM1		
		Ar=0	Ar=0		
		Xe=0	O2=0	Target angle=55	
		N2=0	N2=0		
Ignite	Ignite_HiV_00_Asst				
		Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam at step=shutoff	Beam at step=ExtractBeam		
		Beam at end=shutoff	Beam at end=PlasmaOnly		
		PBN=off	PBN=on		
		Beam voltage=0	Beam voltage=900	PM1	Process time
		Beam current=0	Beam current=160	Si	20sec
		Ignition RF Power=0	Ignition RF Power=150		
		Suppressor Voltage=0	Suppressor Voltage=180		Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5		substrate=close
		K Factor=0	K Factor=3.1		target=close
		Gas Values	Gas Values	Target angle=55	
		PM1	PM1		
		Ar=10	Ar=10		
		Xe=0	O2=0		
		N2=0	N2=0		
Ignite_HiV_01_DepoAsst					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam at step=shutoff	Beam at step=ExtractBeam		
		Beam at end=shutoff	Beam at end=ExtractBeam		
		PBN=on	PBN=on		
		Beam voltage=1120	Beam voltage=900	PM1	Process time
		Beam current=200	Beam current=200	Si	20sec
		Ignition RF Power=150	Ignition RF Power=150		
		Suppressor Voltage=150	Suppressor Voltage=180		Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5		substrate=close
		K Factor=3.1	K Factor=3.1		target=close
		Gas Values	Gas Values	Target angle=55	
		PM1	PM1		
		Ar=10	Ar=10		
		Xe=0	O2=0		
		N2=0	N2=0		

	Ignite_GridClean	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
	Beam at step=ExtractBeam	Beam at step=ExtractBeam				
	Beam at end=PlasmaOnly	Beam at end=PlasmaOnly				
	PBN=on	PBN=on				
	Beam voltage=50	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40	
	Beam current=310	Beam current=310	Si	300sec	Fixture Rotation Speed=20rpm	
	Ignition RF Power=250	Ignition RF Power=250				
	Suppressor Voltage=800	Suppressor Voltage=800			Shutter "at beam"	
	PBN Flowrate=5	PBN Flowrate=5			substrate=close	
	K Factor=2	K Factor=2			target=close	
	Gas Values	Gas Values	Target angle=55			
	PM1	PM1				
	Ar=10	Ar=10				
	Xe=0	O2=0				
	N2=0	N2=0				
Warmup	Warm up	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
	Beam at step=PlasmaOnly	Beam at step=PlasmaOnly				
	Beam at end=PlasmaOnly	Beam at end=PlasmaOnly				
	PBN=on	PBN=on				
	Do not change RF	Do not change RF				
	Beam voltage=50	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40	
	Beam current=380	Beam current=400	Si	10sec	Fixture Rotation Speed=10rpm	
	Ignition RF Power=300	Ignition RF Power=300				
	Suppressor Voltage=800	Suppressor Voltage=795			Shutter "at beam"	
	PBN Flowrate=5	PBN Flowrate=5			substrate=close	
	K Factor=2	K Factor=2			target=close	
	Gas Values	Gas Values	Target angle=55			
	PM1	PM1				
	Ar=10	Ar=10				
	Xe=0	O2=0				
	N2=0	N2=0				
SiN_GasRamp	SiN_GasRamp	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
	Beam at step=PlasmaOnly	Beam at step=PlasmaOnly				
	Beam at end=PlasmaOnly	Beam at end=PlasmaOnly				
	PBN=on	PBN=on				
	Do not change RF	Do not change RF				
	Beam voltage=950	Beam voltage=60	PM1	Process time	Fixture Tilt Angle=40	
	Beam current=380	Beam current=310	Si	15sec	Fixture Rotation Speed=20rpm	
	Ignition RF Power=300	Ignition RF Power=300				
	Suppressor Voltage=153	Suppressor Voltage=960			Shutter "at beam"	
	PBN Flowrate=5	PBN Flowrate=5			substrate=close	
	K Factor=2	K Factor=2			target=close	
	Gas Values	Gas Values	Target angle=55			
	PM1	PM1				
	Ar=10	Ar=5				
	Xe=5	O2=0				
	N2=0	N2=10				
SiN_PreSputter	SiN_PreDep1_Gas Stab.					

	<b>Depo Beam Parameters</b>	<b>Assist Beam Parameters</b>	<b>Target</b>	<b>Process</b>	<b>Fixture</b>
	Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
	Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
	PBN=on	PBN=on			
	Do not change RF	Do not change RF			
	Beam voltage=950	Beam voltage=60	PM1	Process time	Fixture Tilt Angle=40
	Beam current=380	Beam current=310	Si	60sec	Fixture Rotation Speed=20rpm
	Ignition RF Power=300	Ignition RF Power=300			
	Suppressor Voltage=153	Suppressor Voltage=960			<b>Shutter "at beam"</b>
	PBN Flowrate=5	PBN Flowrate=5			substrate=close
	K Factor=2	K Factor=2			target=close
	<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
	PM1	PM1			
	Ar=0	Ar=0			
	Xe=5	O2=0			
	N2=0	N2=30			
<b>SiN_PreDep2_Sputter</b>					
	<b>Depo Beam Parameters</b>	<b>Assist Beam Parameters</b>	<b>Target</b>	<b>Process</b>	<b>Fixture</b>
	Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
	Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
	PBN=on	PBN=on			
	Do not change RF	Do not change RF			
	Beam voltage=950	Beam voltage=60	PM1	Process time	Fixture Tilt Angle=40
	Beam current=380	Beam current=310	Si	300sec	Fixture Rotation Speed=20rpm
	Ignition RF Power=300	Ignition RF Power=300			
	Suppressor Voltage=153	Suppressor Voltage=960			<b>Shutter "at beam"</b>
	PBN Flowrate=5	PBN Flowrate=5			substrate=close
	K Factor=2	K Factor=2			target=close
	<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
	PM1	PM1			
	Ar=0	Ar=0			
	Xe=5	O2=0			
	N2=0	N2=30			
<b>SiN_Dep</b>					
	<b>Depo Beam Parameters</b>	<b>Assist Beam Parameters</b>	<b>Target</b>	<b>Process</b>	<b>Fixture</b>
	Beam at step=ExtractOnly	Beam at step=ExtractOnly			
	Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
	PBN=on	PBN=on			
	Beam voltage=950	Beam voltage=60	PM1	Process time	Fixture Tilt Angle=40
	Beam current=380	Beam current=310	Si	1800sec	Fixture Rotation Speed=20rpm
	Ignition RF Power=300	Ignition RF Power=300			
	Suppressor Voltage=153	Suppressor Voltage=960			<b>Shutter "at beam"</b>
	PBN Flowrate=5	PBN Flowrate=5			substrate=open
	K Factor=2	K Factor=2			target=open
	<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
	PM1	PM1			
	Ar=0	Ar=0			
	Xe=5	O2=0			
	N2=0	N2=30			

SiN_GasRamp	SiN_GasRamp	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=950	Beam voltage=60	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=310	Si	15sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=153	Suppressor Voltage=960			
		PBN Flowrate=5	PBN Flowrate=5			
		K Factor=2	K Factor=2			
		<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=5			
		Xe=5	O2=0			
		N2=0	N2=10			
SiN_GridClean	SiN_GridClean	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=ExtractOnly	Beam at step=ExtractOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Beam voltage=50	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam current=310	Beam current=310	Si	300sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=375	Ignition RF Power=375			
		Suppressor Voltage=800	Suppressor Voltage=800			
		PBN Flowrate=5	PBN Flowrate=5			
		K Factor=2	K Factor=2			
		<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	Xe=0			
		N2=0	N2=0			
Shut_n_pmp_du	Shut_n_pmp_dwn	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=shutoff	Beam at step=shutoff			
		Beam at end=shutoff	Beam at end=shutoff			
		PBN=off	PBN=off			
		Beam voltage=0	Beam voltage=0	PM1	Process time	Fixture Tilt Angle=40
		Beam current=0	Beam current=0	Si	30sec	Fixture Rotation Speed=10rpm
		Ignition RF Power=0	Ignition RF Power=0			
		Suppressor Voltage=0	Suppressor Voltage=0			
		PBN Flowrate=0	PBN Flowrate=0			
		K Factor=0	K Factor=0			
		<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=0	Xe=0			
		N2=0	N2=0			
Shut_dwn_open_cryo		Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=shutoff	Beam at step=shutoff			
		Beam at end=shutoff	Beam at end=shutoff			
		PBN=off	PBN=off			
		Beam voltage=0	Beam voltage=0	PM1	Process time	Fixture Tilt Angle=90
		Beam current=0	Beam current=0	Si	10sec	Fixture Rotation Speed=10rpm
		Ignition RF Power=0	Ignition RF Power=0			
		Suppressor Voltage=0	Suppressor Voltage=0			
		PBN Flowrate=0	PBN Flowrate=0			
		K Factor=0	K Factor=0			
		<b>Gas Values</b>	<b>Gas Values</b>	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=0	Xe=0			
		N2=0	N2=0			